				Search Text			Error Definition	Er
))	BRS	L1		wafer and balch\$3 nearl process\$3		 Training the principle of the principle 		0
2	BRS	L2	5	l and workpiece and tool and state and metrology and rout\$3 and correlation	T:			0
3	IS&R	L3	1	("6773931").PN.	<u> </u>	2004/10/15 19:44		0
4	BRS	L4	1	3 and fault		2004/10/15 19:45		0
5	BRS	L5	1	3 and (fault or error)	USPA T; US-P GPUB			0
6	BRS	L6	1	5 and detect\$3		•		0
7	BRS	L7	0	3 and position		• • • • • • • • • • • • • • • • • • • •		0
8	BRS	L8	0	3 and modify\$3	USPA T; US-P GPUB			0
9	BRS	L9	0	3 and queue	USPA	2004/10/15 19:52		0
10	BRS	L10	Ò	3 and sampl\$3	USPA	2004/10/15 19:53		Ö
11	BRS	LII	0	3 and trigger		:		0
12	BRS	L12	1	3 and trigger\$3	2			O
13	BRS	L13	1	"6587744" PN.		2004/10/15 19:56		0
14	BRS	L14	1	"6444481".PN.	. *. * . * . * . * . * . * .	2004/10/15 19:56		0
15	BRS	L15	1	"6408220" PN		2004/10/15 19:57		0
16	BRS	L16	1	"5270222" PN		2004/10/15 19:57		0
17	BRS	L17	1	"6587744".PN		2004/10/15 19:58		0
20000	SI							<i>x</i> ;

Fast seach Notes

		n n	Document II US 20040059456 A1	20040325		Title Correlating an inline parameter to a device operation parameter	700/121	Current XR Retrieval (Inventor Bode, Christopher A. et	S	
	1	r r	US 20040029299 A1	20040212	20	Dynamic targeting for a process control system	438/5	700/121	Pasadyn, Alexander J et al.	Þ	
	Г	r r	US 20010039462 A1	20011108	28	System and method for predicting software models using material-centric process instrumentation	700/45		Mendez, Rafael et al.	Þ	f
	r	r. r	US 6773931 B2	20040810	19	Dynamic targeting for a process control system	438/10	700/121	Pasadyn, Alexander J. et al.	Þ	
P	T. C.	r r	US 6650955 B1	20031118	9	Method and apparatus for determining a sampling plan based on process and equipment fingerprinting	700/108	438/14; 438/16; 438/17; 438/18; 700/109; 700/110; 702/83	Sonderman, Thomas J. et al.	Ē	